



Docket No.: 200669US0DIV

ASSISTANT COMMISSIONER FOR PATENTS
WASHINGTON, D.C. 20231



ATTORNEYS AT LAW

RE: Application Serial No.: 09/736,147
Applicants: Yasuo KOBAYASHI, et al.
Filing Date: December 15, 2000
For: PROCESSING METHOD AND APPARATUS FOR
REMOVING OXIDE FILM
Group Art Unit: 1763
Examiner: DANG, T.D.

SIR:

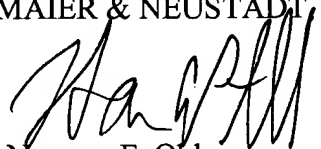
Attached hereto for filing are the following papers:

AMENDMENT WITH MARKED-UP COPY (10 PAGES)

Our check in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,
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IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF :
YASUO KOBAYASHI ET AL : EXAMINER: DANG, T. D.
SERIAL NO: 09/736,147 :
FILED: DECEMBER 15, 2000 : GROUP ART UNIT: 1763
FOR: PROCESSING METHOD AND :
APPARATUS FOR REMOVING
OXIDE FILM

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AMENDMENT

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SIR:

Responsive to the Office Action dated March 20, 2002, Applicants respectfully request reconsideration of the above-identified application in view of the following amendment and remarks.

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IN THE CLAIMS

Please cancel all the claims and replace with new Claims 32-51 as follows:

Sub C > 32. (New) A surface treatment apparatus comprising:
a plasma generation section for generating plasma from a plasma generating gas,
a treatment vessel connected to the plasma generation section and including a
susceptor on which a subject to be treated is placed;

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